

Publication policy of Journal of Laser Micro/Nanoengineering

Preface

Journal of Laser Micro/Nanoengineering, founded in 2005 by Japan Laser Processing Society (JLPS), is an international on-line journal for the rapid publication of experimental and theoretical investigations in laser-based technology for micro- and nano-engineering. Four issues per year are published, which constitute one volume. Access to the full article is provided free of charge.

The submitted manuscript must have been neither copyrighted, classified, published, nor be being considered for publication elsewhere except for LPM proceedings.

The authors can submit a manuscript to this Journal anytime. In addition, the authors who submit their proceedings manuscripts for LPM symposium organized by JLPS have a chance to publish them in this Journal. The submitted manuscripts are peer reviewed.

Once a manuscript has been accepted, it is published on line at URL of :

<http://www.jlps.gr.jp/jlmn>
quickly and free of charges.

Topics

Topics of this journal include laser-based technology for the following subjects, but not limited to;

1. Fundamental aspects (Dynamics, Modeling, Simulation, etc.)
2. Process monitoring and control
3. Nanotechnology
4. Direct write process (MAPLE-DW, LIFT, etc.)
5. Ultra-short pulse laser processing
6. VUV laser processing
7. Surface treatment (Texturing, Cleaning, Annealing, modification, etc.)
8. Micro-patterning and micro-structuring
9. Micro-machining
10. 3-D micro- and nano-fabrication
11. Drilling and cutting
12. Welding and bonding
13. Micro-forming
14. Wafer dicing
15. Marking and trimming
16. Packaging and mounting process
17. Lithography (including EUV Source and Application)
18. Manufacture of micro devices and systems
19. Film deposition and synthesis of advanced

materials (PLD, CVD, etc)

20. Nano- and micro-particles
21. Medical and biological applications
22. Optics and systems for laser microprocessing
23. Laser devices
24. Industrial applications
25. Photochemistry
26. Glass/Ceramic processing

Instructions for Authors

Submission of manuscript

Original manuscripts should be submitted to the following address, along with a CD that includes both a PDF and Microsoft Word file of their papers by post or business mail. Each manuscript must be accompanied by a completed and signed copyright transfer statement. The copyright transfer form is available at URL of <http://www.jlps.gr.jp/jlmn>

Sending address:

Journal of Laser Micro/Nanoengineering
JLPS-Japan Laser Processing Society
C/o Katayama Lab., JWRI-Joining and
Welding Research Institute, Osaka University
11-1 Mihogaoka, Ibaraki, Osaka, 567-0047,
Japan
Tel/Fax: +81-6-6879-8642,
E-mail: jlmn@jlps.gr.jp

Manuscripts sent to authors for revision should be returned to the Editor within three months after revisions based on the reviewer's comments. A manuscript returned after this period will generally be regarded as newly submitted and will receive a new receipt date.

Suggestion of possible reviewers

The authors can suggest possible reviewers. To help protect the reviewer's anonymity, the authors must nominate at least three names, with full information on postal and e-mail addresses, telephone number, and fax number. The reviewer may, of course, not be selected from the list.

How to prepare your manuscript

The instruction manual and template are available at URL of <http://www.jlps.gr.jp/jlmn>

Reprints

If you wish to order reprints, you must send the reprint order form with the corrected proofs. The reprint order form is available at URL of <http://www.jlps.gr.jp/jlmn>